

# Planar SiC Schottky Diodes

Studying Material properties, traps, irradiation effects, annealing  
Towards a Radiation Damage Model

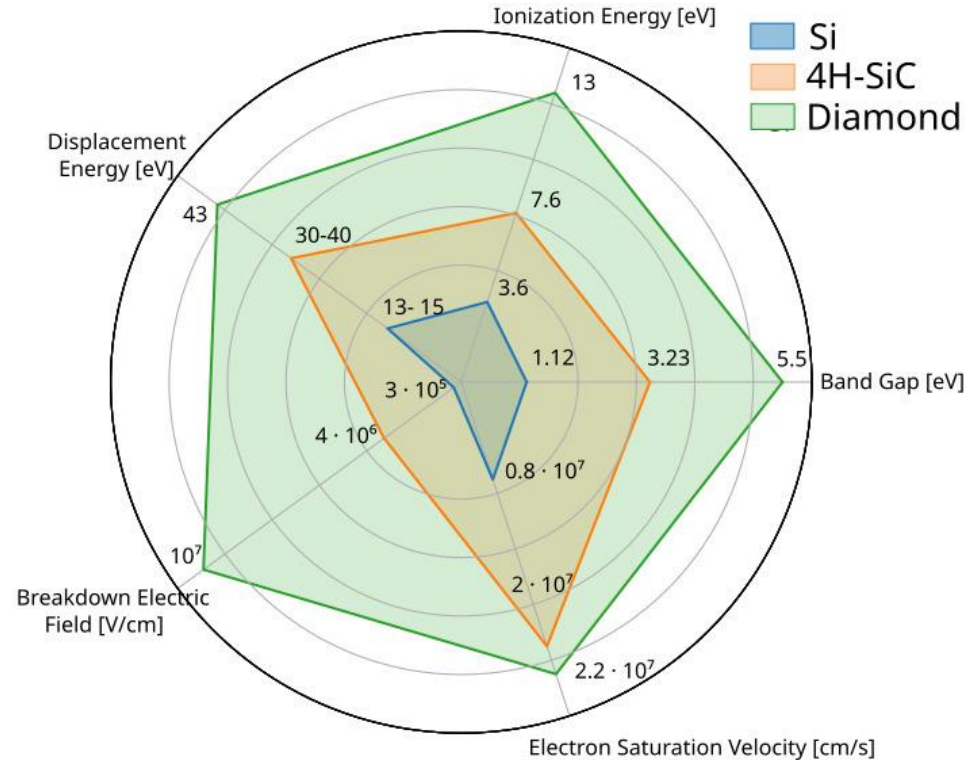
DRD3 WG6 Project Proposal

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DRD3 WBG Meeting , 10.10.2024

# Silicon Carbide

- Wide bandgap material
  - One of first investigated semiconductors
  - Used in power electronics
  - Polytype 4H commonly used
- Features high
  - Charge carrier mobilities
  - Breakdown field
  - Thermal conductance
- Utilization @ HEPHY
  - Low noise particle detector
  - Medical and HEP applications



# Radiation Damage in SiC: Open Challenges

- Open challenges in radiation damage modelling for SiC:
  - Trap information deviate in literature
  - Existing models are based on small sample sizes and specific fluences
  - Integration of a dedicated model in TCAD
- Demand for large-scale irradiation study:
  - Statistically significant sample size (>? devices)
  - Large spectrum of fluences  $10^{13} n_{eq}/cm^2$  -  $10^{18} n_{eq}/cm^2$
- **However: not enough sensor samples available**
- **Proposal:**
  - **irradiation study with commercially available SiC-Schottky diodes on the short term**
  - **Production of planar Schottky and pn-junction diodes**

# Available SiC Producers

- CNM Barcelona
  - Had a couple of runs already
  - Currently too many other projects
  - Delays
- FBK Trento
  - Plan to start SiC processing
  - First run with Schottky, second run with pn-junction diodes
- Fraunhofer IISB
  - CMOS SiC process with  $2\mu\text{m}$

# Commercial SiC Schottky Diodes

- Increasing availability due to demand in power electronics (BV of up to 3kV,  $I_f$  up to 40A)
- Can be obtained online & off the shelf in large numbers
- Cheap: a few cents per diode
- Come with validated characteristics, datasheets and SPICE models
- Expected depletion region thickness of 4-7 $\mu$ m
  - challenge for MIP detection
  - laser and alpha particle measurements preferred for radiation sensing
- Have metal contact on top → metallization needs to be removed for laser tests

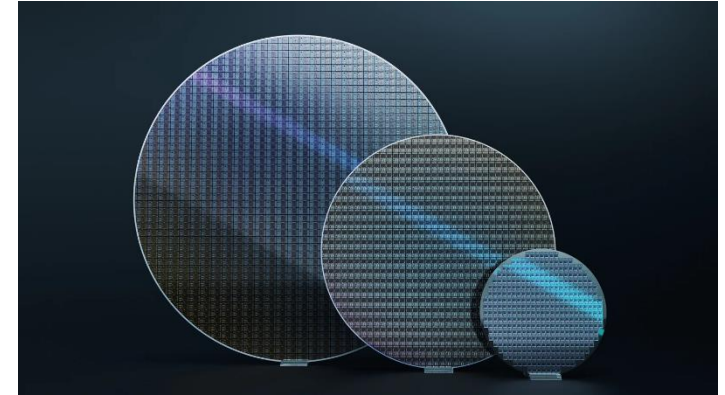
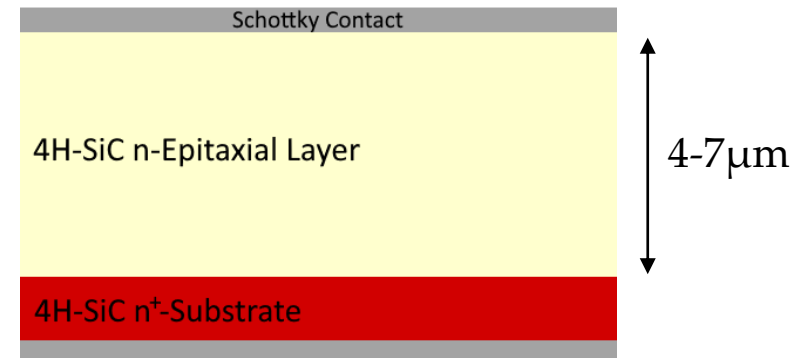
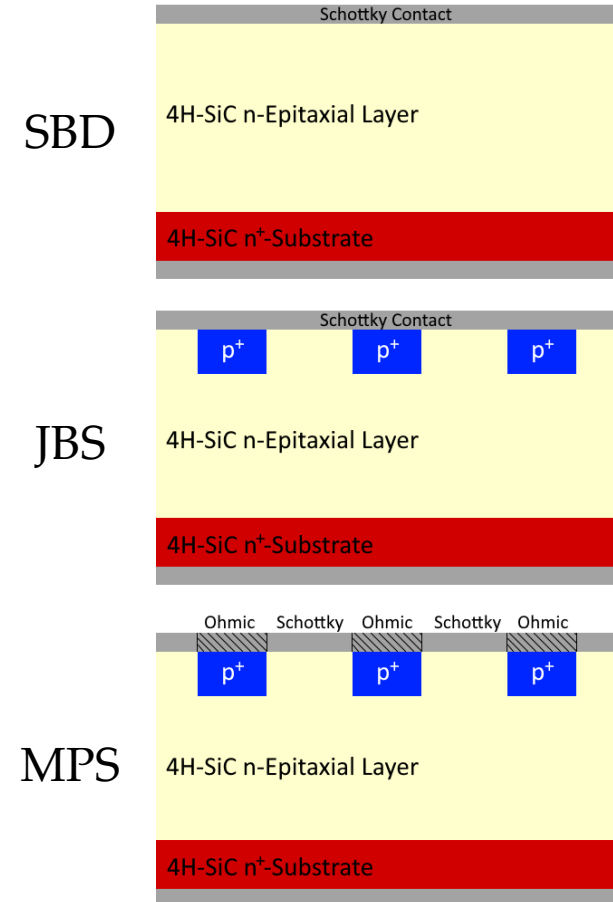


Image from: <https://questsemi.com/products/copy-of-copy-of-qs-hcs-6510-650v-10a>



# Types of SiC Schottky Diodes

- Schottky Barrier Diode (SBD)
  - p-implants with Schottky contact to metal
  - Reduction of leakage current in reverse bias
- Junction Barrier Schottky (JBS) Diode
  - P-implants with ohmic contact to metal
  - Reduction of leakage current in reverse bias
  - PN-junction dominates forward current at high forward voltages → better thermal stability
- MPS diodes offer best performance for power applications
  - mostly MPS diodes available online
  - TCAD modelling becomes more complex

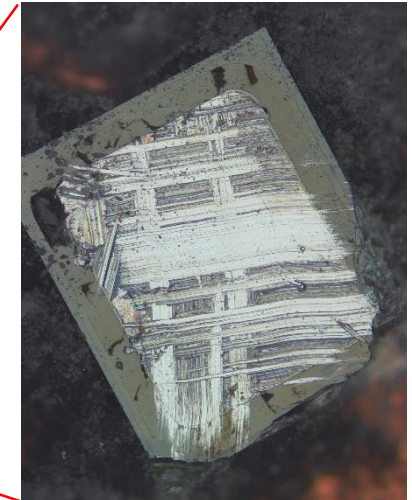


# Availability of Bare Dies

- **For radiation sensing: need for bare dies**
- Several vendors offer bare dies: Central Semiconductor, WolfSpeed, SemiQ, LeapSiC...
- However: first contact approaches for small number of samples were left unanswered
- Workaround 1: open packaged diodes
  - Opening packages is tedious for >? samples
  - Destruction-free opening still an open question
- Workaround 2: commercial production run
  - Advantages:
    - Custom structure → easier reverse engineering of TCAD models
    - Diodes tailored for radiation sensing → thick epi-layer, simple architecture, metallization opening for laser tests
  - Disadvantages: possibly higher costs and lead times



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# Plan/Deliverables: Measurements

- Selection and commissioning of samples:
  - Multiple devices, e.g. differing substrate doping, IV/CV characteristics
  - If possible, different manufacturers
  - >? samples per combination
- Irradiation campaign
  - Fluences of  $10^{13} n_{\text{eq}}/\text{cm}^2$  -  $10^{18} n_{\text{eq}}/\text{cm}^2$  (EURO-LABS)
  - Irradiation with different particles (neutron, proton, electron,  $\gamma$ )
  - $\geq 3$  devices per fluence and particle
- Pre/post irradiation measurements
  - IV, CV, CCE, DLTS, MCTS, . . .
  - unchanged measurement setups
  - with(out) thermal annealing





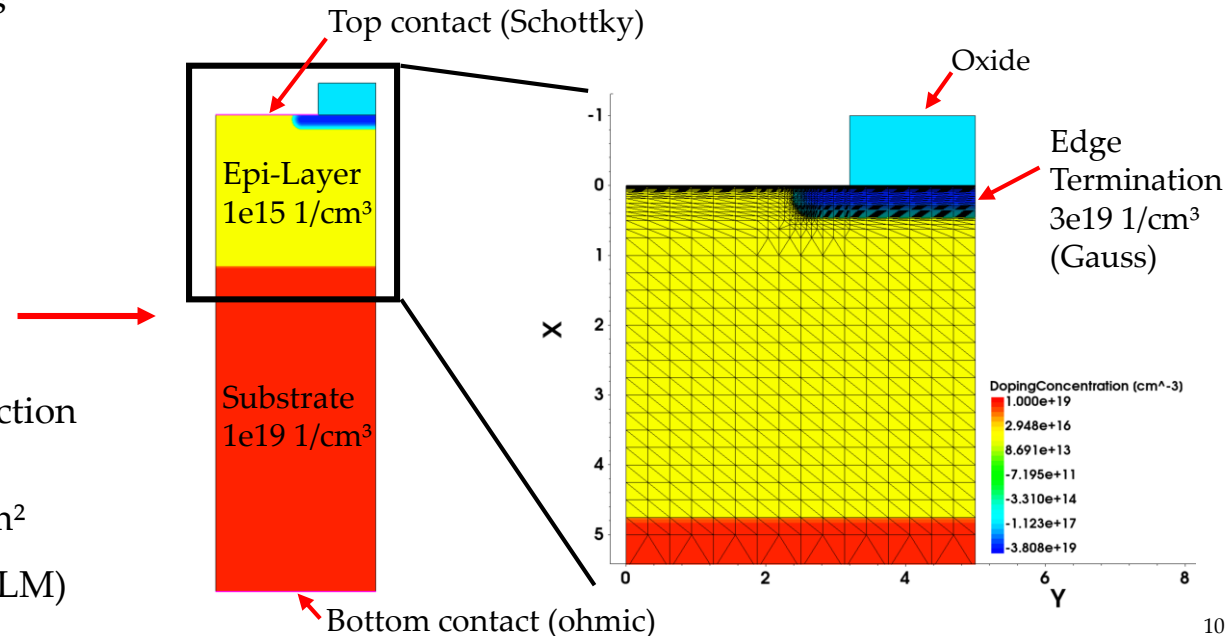
# Plan/Deliverables: Simulation

- TCAD reverse engineering: reconstruction of IV, CV and CCE characteristics
- Additional information available through:
  - SEM, TEM and SIMS measurements for device structuring
  - SPICE models
  - If devices from production run: TCAD models maybe offered by manufacturer
- Model fitting based on measurements from irradiated samples:
  - traps
  - type (donor/acceptor)
  - ionization energy
  - introduction rate
  - electron/hole capture cross sections



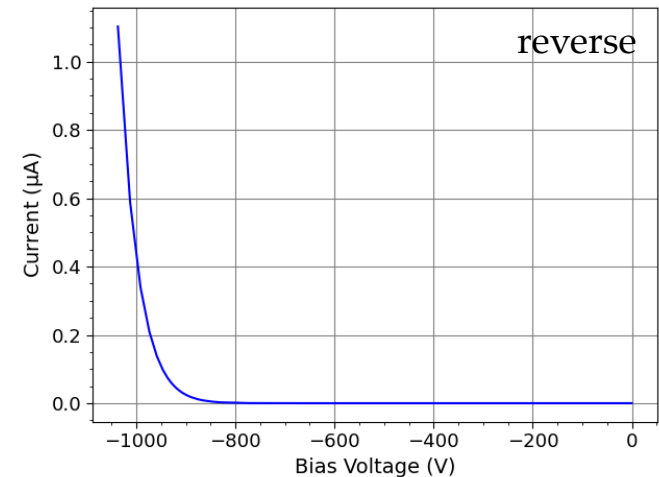
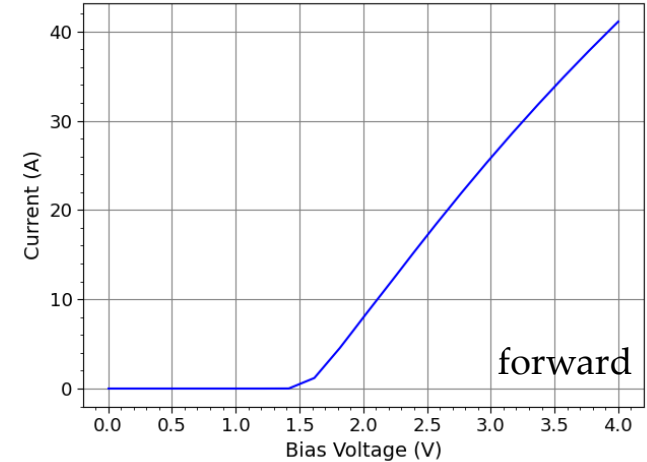
# TCAD Challenge

- Main challenge: reverse engineering of unirradiated devices
- Large parameter space:
  - Work function energy (depends on metallization)
  - Substrate doping (higher doping = higher tunneling current)
  - Schottky barrier tunneling parameters
  - Diode architecture (SBD, JBS, MPS)
  - Recombination, impact ionization, ...
- Starting point: SiC Schottky diode template in Sentaurus TCAD [1]
  - Schottky contact with 5.1eV work function energy
  - Area Factor:  $2e5$  -> device area of  $1\text{mm}^2$
  - Non-local barrier tunneling model (NLM)



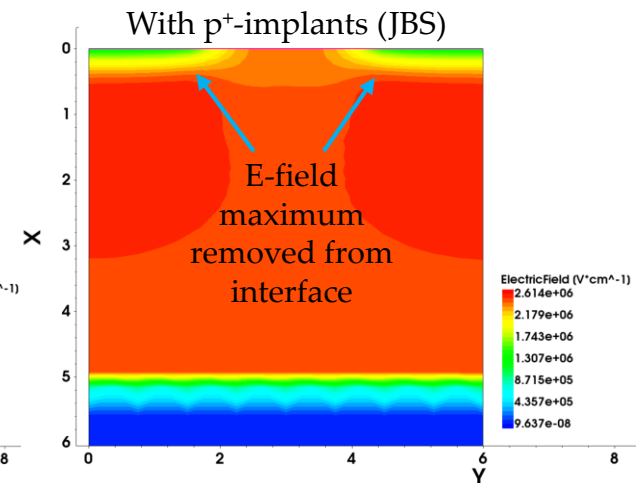
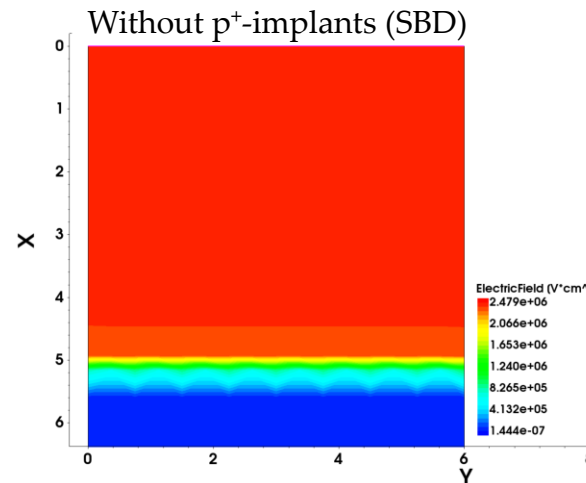
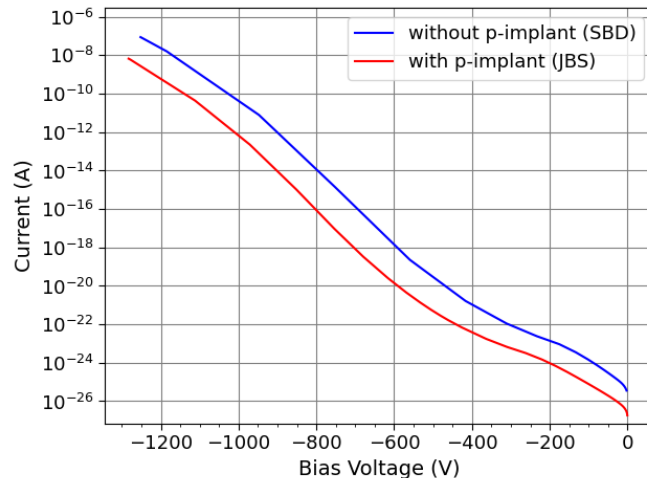
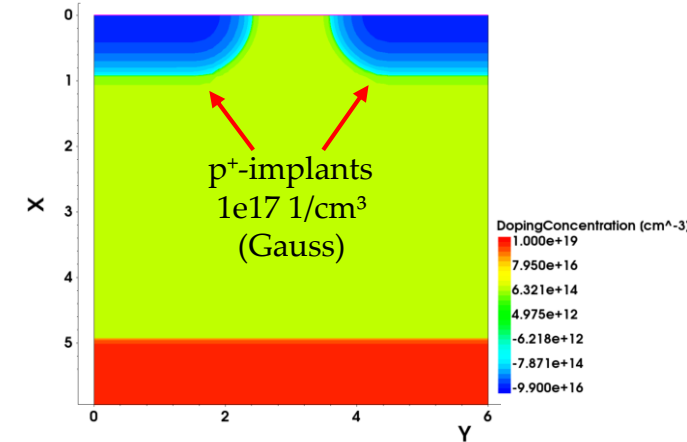
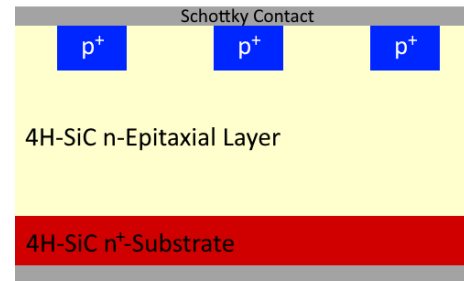
# Sentaurus SiC Schottky Template

- Forward IV:
  - $V_{on} \approx 1.4V$
  - Forward current in the same ballpark as commercially available diodes
- Reverse IV:
  - breakdown starts at  $\sim 900V$
  - Commercial devices have breakdown at 650V up to  $\sim 3000V$  (1200V most popular)



# First Simulation Efforts for JBS Diode

- From SiC Schottky template:
  - Oxide and edge termination removed
  - p<sup>+</sup>-implants added
- Electric field lowered at metal-semiconductor interface
- Reduced leakage current



# Possible Contributions

- **HEPHY Vienna:** irradiation campaign, lab measurements, test beam @ Medaustron, TCAD simulations
- **INFN Perugia:** TCAD simulation, lab measurements
- **FBK:** production of Schottky and pn-junction 4H-SiC diodes
- **INFIM Romania** (Ioana Pintilie): defect investigations, FTIR and Hall measurements
- **INFN Torino**

